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15 JAN 2002
SHEET 1 OF 1

FORM PTO-1449 (SUBSTITUTE)				Attorney Docket No : 2000P1907			
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE				Applicant VIRINDER GREWAL ET AL.			
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (37 CFR 1.98(b))				Filing Date January 16, 2002			

EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
ge	A	5,948,703	09/99	Shen et al.			
	B	5,874,363	02/99	Hoh et al.			
	C	5,843,239	12/98	Shrotriya			
	D	5,583,737	12/96	Collins et al.			
	E	5,158,644	10/92	Cheung et al.			
	F	5,591,301	01/97	Grewal			
ge	G	5,529,197	06/96	Grewal			
	H						
	I						

FOREIGN PATENT DOCUMENT							
		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES NO
ge	J	0 814 501 A3	12/97	Europe			X
	K	0 746 015 A2	12/96	Europe			X
1/98	L	0 718 868 A2	06/96	Europe			X
	M						
	N						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)	
ge	Japanese Patent Abstracts 09045671 A (Yamazaki Shunpei) dated February 14, 1997
ge	"Challenges for 300 mm Plasma Etch System Development", Sanjay Tandon, XP-000974462, March 1998, Semiconductor International, pp. 75-82
EXAMINER	DATE CONSIDERED 10/19/03

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609.
Draw line through citation if not in conformance and not considered. Include copy of this form with
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